What is claimed is:

1. An apparatus, comprising:
a pellicle fused to a frame; and
a reticle attached to the frame.

2. The apparatus of claim 1, wherein:
the reticle is fused to the frame.

3. The apparatus of claim 1, wherein:
the reticle comprises fused silica.

4. The apparatus of claim 3, wherein:
the frame comprises fused silica.

5. The apparatus of claim 1, wherein:
the reticle is to be used in a lithographic exposure operation in manufacturing integrated circuits.

6. The apparatus of claim 1, wherein:
the pellicle comprises fused silica.

7. The apparatus of claim 6, wherein:
the frame comprises fused silica.

8. The apparatus of claim 1, wherein:

the pellicle is fused to the frame along a seam between the pellicle and the frame.

9. The apparatus of claim 1, wherein:

the pellicle has a local tilt of less than 10 microradians.

10. A method, comprising:

fusing a pellicle to a frame at a first seam between the pellicle and the frame; and

attaching the frame to a reticle.

11. The method of claim 10, wherein:

said attaching the frame comprises fusing the frame to the reticle.

12. The method of claim 11, wherein:

said fusing the pellicle to the frame occurs approximately concurrently with said fusing the frame to the reticle.

13. The method of claim 10, wherein:

said fusing the pellicle to the frame occurs before said attaching the frame to the reticle.

14. The method of claim 10, wherein:

said fusing the pellicle to the frame occurs after said attaching the frame to the reticle.

15. The method of claim 10, wherein:
said fusing the pellicle to the frame comprises using a laser beam.

16. The method of claim 15, wherein:
said using the laser beam comprises using an infrared laser beam.

17. The method of claim 16, wherein:
said infrared laser beam is produced by a CO_2 laser.

18. A system, comprising:
a support to hold a pellicle and a frame in place for a fusion attachment between the pellicle and the frame;
a laser device to fuse the pellicle to the frame;
a structure to position a first seam between the pellicle and the frame in a path of a laser beam from the laser device; and
a control device to move at least one of the pellicle and the laser relative to one another to move at least a part of the first seam through the path of the laser beam.

19. The system of claim 18, wherein:
the support is further to hold the frame and a reticle in place for attachment to one another.

20. The system of claim 18, wherein:

the control device is to move at least one of the pellicle and the laser relative to one another to move all of the first seam through the path of the laser beam.

21. The system of claim 18, wherein:

the laser device comprises a CO_2 laser.

22. The system of claim 18, wherein:

the support is further to hold a reticle and the frame in place for a fusion attachment to one another;

the laser device is further to fuse the frame to the reticle;

the structure is further to position a second seam between the frame and the reticle in the path of the laser beam from the laser device; and

the control device is further to move at least one of the reticle and the laser device relative to one another to move at least a part of the second seam through the path of the laser beam.